



THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Confirmation No. 9191

Makoto AKIZUKI et al.

Docket No. 2001-1897

Serial No. 10/025,899

Group Art Unit 1762

Filed December 26, 2001

Examiner Bernard D. Pianalto

**METHOD FOR FORMING GAS CLUSTER AND
METHOD FOR FORMING THIN FILM**

RECEIVED
AUG 29 2003
TC 1700

PETITION FOR EXTENSION OF TIME

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Petition hereby is made for a three month extension of time to respond to the communication of February 27, 2003.

The fee of \$930.00 is

submitted herewith.
 to be charged to Deposit Account No. 23-0975. A duplicate copy of this Petition is enclosed.

 Small entity status of this application is established by a Small Entity Status Assertion which
 is enclosed.
 has been previously submitted.

Respectfully submitted,

Makoto AKIZUKI et al.

By Matthew Jacob

Matthew Jacob
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August 27, 2003

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